

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

1-8. (Cancelled).

9. (Currently Amended) A micro electromechanical switching arrangement, comprising:

a switching element comprising including a first support, an actuator control electrode, and a switching beam having a first end and a second end, the first end of the switching beam being supported by the first support, characterized in that the ~~micro electromechanical switching arrangement further comprises:~~

[ - ] a switching beam position measurement device, which generates for generating a beam position signal related to a position of the switching beam in relation to a position of the actuator control electrode; and

[ - ] an actuator control signal unit, which generates for generating an actuator control signal in dependence on the beam position signal and a desired switching beam position signal, the actuator control signal being coupled to the actuator control electrode.

10. (Currently Amended) The micro electromechanical switching arrangement according to claim 9, characterized in that: wherein [ - ] the switching element further comprises a second support, the second end of the switching beam being supported by the second support.

11. (Currently Amended) The micro electromechanical switching arrangement according to claim 9, characterized in that: wherein [-] the switching beam position measurement device utilizes is configured to use capacitive measurement methods for generating the beam position signal.

12. (Currently Amended) The micro electromechanical switching arrangement according to claim 9, characterized in that: wherein [-] the switching beam position measurement device comprises a variable capacitance element and a Wheatstone bridge in which the variable capacitive device is one element.